FOUP300 VAC.LOADPORT

direct loading of wafers into vacuum environment

ADVANTAGES:
✓ STANDARD FOUP front opening universal pod according semi standard
✓ DIRECT LOAD INTO VACUUM the vacuum handler take the wafer direct from the FOUP
✓ NO ATMOSPHERIC HANDLING there are no ATM handling robot / load ports necessary
✓ FOOTPRINT saves up to 80% of floor space
✓ COMPLEXITY save invest and operating costs with Adenso.Solutions

solutions you need
www.waferhandling.solutions
FOUP300 VAC.LOADPORT

direct loading of wafers
into vacuum environment

Advantages
✓ higher productivity
✓ more cleanroom space
✓ optimized costs
✓ greater flexibility
✓ progressive products
✓ new markets
✓ ...

The blue Adenso.Solution

Smart with a small footprint and a lot of advantages for Adenso.Clients
For loading 300mm wafer into cluster systems directly and without (!) atmospheric handling robots. The complete handling module with two FOUP300-VAC.LOADPORTS is located inside the area marked in blue.
Current solutions require area marked in grey as well as atmospheric robot handling, which not only takes space, but involves invest costs and running operating costs.

Footprint
Saves up to 80% of cleanroom floor space.
Saves investment and operating costs for unnecessary tools.

Layout top view
Dimensions of a cluster system with 2pcs. of Adenso FOUP VAC.LOADPORT compared to state of the art 300mm wafer loadings.

Discover new possibilities to build up new business segments!

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